

ABSTRACT OF THE DISCLOSURE

SUBSTRATE TREATING APPARATUS AND SUBSTRATE TREATING METHOD

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An embodiment includes a substrate treating apparatus and a substrate treating method. The substrate treating apparatus comprising: an equipment front end module (EFEM) having a load port and an index robot; a process chamber; a transfer chamber having a transfer robot for carrying in or carrying out the substrate in
10 respective to the process chamber; and a loadlock chamber positioned between the transfer chamber and the EFEM, and having a substrate support unit for supporting a substrate and a cover support unit for supporting a cover which may cover outer circumference of the substrate.

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FIG. 2